

IESA DeepTech Hackathon PS01(PHASE-1)

Edge-AI-Based Defect Classification System for Semiconductor Images

| Team Details

Team Name: Bandgap

SR. NO	ROLE	NAME	ACADEMIC YEAR
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Problem Statement Addressed

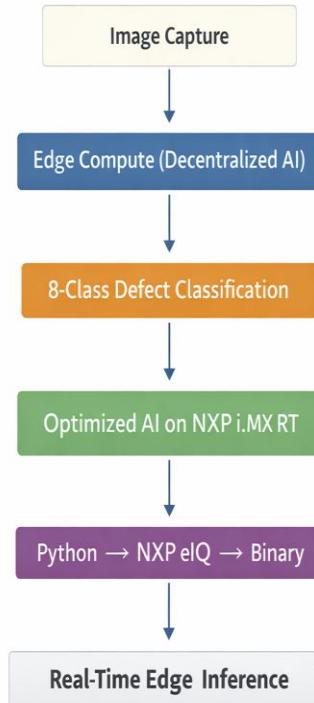
- **Real-Time Edge Intelligence:** Replaces slow, cloud-based manual inspection with on-device Edge AI, enabling instant defect analysis at fabrication-line speeds.
- **Hardware-Aware AI Design:** Delivers high-accuracy defect classification using lean models optimized for the strict power and memory constraints of NXP i.MX RT devices
- **Fab-Level Intelligence Shift:** Moves decision-making from the cloud directly to the manufacturing tool, improving yield and supporting India's deep-tech manufacturing ecosystem.
- **Python-to-Silicon Deployment:** Bridges software and hardware using the NXP eIQ platform to convert Python-based AI models into deployable binaries for embedded execution.

Idea Description

- Decentralized Intelligence Architecture: Our solution moves computational load from high-latency servers directly to the manufacturing edge for real-time defect identification.
- High-Fidelity Categorization Engine: The system utilizes a robust 8-class classification model to detect "Clean" wafers versus sub-micron structural failures like Bridges, Cracks, and LER.
- Resource-Efficient Model Engineering: We engineer lean AI models optimized for the low-power and memory-constrained environments of NXP i.MX RT series devices.
- Automated Toolchain Integration: We bridge the gap from Python to silicon by using the NXP eIQ platform to transform abstract code into deployable hardware bit-files.

Proposed Solution

- **Fast edge-level processing:** Inspection images are processed directly at the manufacturing edge using decentralized AI, minimizing latency and eliminating reliance on cloud servers.
- **Reliable defect classification:** An 8-class AI model accurately distinguishes clean samples from multiple defect types, enabling consistent and real-time defect detection.
- **Efficient embedded deployment:** Models are developed in Python and converted into deployable binaries via the NXP eIQ platform, ensuring smooth real-time inference on NXP i.MX RT devices.



TECHNOLOGY & FEASIBILITY

- **Edge AI Processing:** Real-time defect detection is executed directly at the manufacturing edge, minimizing latency and eliminating cloud dependence.
- **Embedded-Ready Hardware:** Lean, optimized AI models run efficiently on low-power **NXP i.MX RT** devices.
- **Seamless Deployment:** Python-based models are converted into deployable binaries using the **NXP eIQ** toolchain.
- **Scalable & Practical:** The solution is easy to replicate across inspection points and feasible for industrial deployment.

DATASET PLAN & CLASS DESIGN

1. Total images planned/current: 6500
2. No. of classes: 8
3. Class list:Bridge, CMP Scratch, Cracks, LER, Opens, Vias, Clean, Other
4. Class balance plan:Minimum 700–850 images per class using controlled augmentation to maintain balance.
5. Train/Val/Test split: 4580(70%) / 960 (15%)/ 960(15%)
6. Image type: Grayscale SEM-style wafer images (structural features preserved, low compute cost)
7. Labeling method/source: Manually labeled samples + public defect references + domain-guided synthetic augmentation.

BASELINE MODEL & RESULTS

1. Architecture: Custom lightweight CNN
2. Training approach: Training from scratch
3. Input size: $128 \times 128 \times 1$ (grayscale)
4. Model size: 8.12 MB
5. Framework: PyTorch

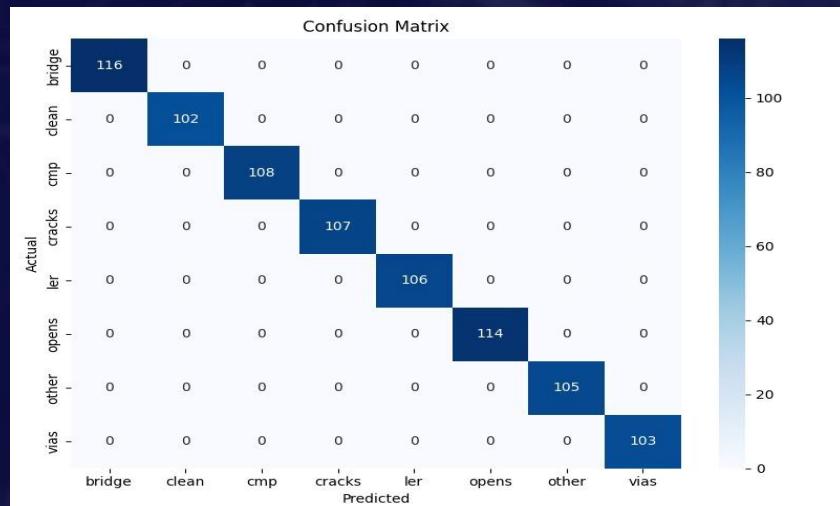
```
C:\nxp_defect_project>python evaluate.py
Classes: ['bridge', 'clean', 'cmp', 'cracks', 'ler', 'opens', 'other', 'vias']

Accuracy: 100.00%

Classification Report:
precision    recall    f1-score   support
bridge       1.00     1.00     1.00      116
clean        1.00     1.00     1.00      102
  cmp         1.00     1.00     1.00      108
cracks       1.00     1.00     1.00      107
  ler         1.00     1.00     1.00      106
  opens       1.00     1.00     1.00      114
  other       1.00     1.00     1.00      105
  vias        1.00     1.00     1.00      103

accuracy          1.00      861
macro avg       1.00     1.00     1.00      861
weighted avg    1.00     1.00     1.00      861

 Confusion matrix saved as confusion_matrix.png
```



GitHub & Dataset Link



GitHub Repository

https://github.com/E-KAMALESH/nxp_deeptechhackathon_bandgap



Dataset

<https://drive.google.com/drive/folders/1j2y6mZkCLwHSvFPWqdYfBAZ2NXhZmfY?usp=sharing>

ONNX Model

https://drive.google.com/drive/folders/1SRTNfe_fsjB8p7BF6VZOvYnoKURrYN6o



Report

<https://drive.google.com/file/d/1ryWWIOy88nr7M5fMI2xJ86t7URwXgfHt/view?usp=drivesdk>



References

- NXP Semiconductors (2024) eIQ Machine Learning Software. Available at: <https://www.nxp.com/eiq> (Accessed: 2024). ONNX (2024) Open Neural Network Exchange. Available at: <https://onnx.ai> (Accessed: 2024). Shi, W., Cao, J., Zhang, Q., Li, Y. and Xu, L. (2016) 'Edge computing: Vision and challenges', IEEE Internet of Things Journal, 3(5), pp. 637–646.